



OXFORD IN YOUR CITY - SAN JOSE

MARCH 26 2020

CLUB AUTO SPORT, CHARCOT AVENUE, SAN JOSE

9.30 - 10.00am	WELCOME & REGISTRATION	
10.00 - 10.15am	Introduction	Emiel Thijssen
10.15 - 11.00am	VCSEL DEVICE MANUFACTURING Low footing process for maximum device performance	Stephanie Baclet
11.00 - 11.15am	COFFEE BREAK	
11.15 - 11.45am	ATOMIC LAYER ETCHING: A new technique for ultra precise and low damage etching	Dr Mark Dineen
11.45 - 12.30pm	ALD FOR GaN POWER DEVICES: Fast plasma enhanced ALD enabling improved interfaces, high quality films & high throughput	Dr Aileen O'Mahony
12.30 - 2.00pm	NETWORKING LUNCH / EXPLORE VENUE	
2.00 - 2.30pm	ATOMIC FORCE MICROSCOPY Recent Developments in Oxford Instruments AFM Solutions	Asylum Research
2.30 - 3.15pm	ION BEAM ETCHING AND DEPOSITION for Laser Facet Processing	Pauline Alvarez
3.15 - 3.30pm	COFFEE BREAK	
3.30 - 4.00pm	RIDGE DRY ETCH & ISOLATION Dry etching of ridge features and for device isolation in InP based materials	Dr Mark Dineen
4.00 - 4.30pm	MICROLED PROCESSING	Stephanie Baclet
4.30 - 4.45pm	Final remarks and close	Emiel Thijssen